

Corrigendum

Corrigendum to “Synthesis of photocatalytic TiO₂ thin films via the high-pressure crystallization process at low temperatures”

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The authors feel sorry for that they supplied the incorrect figure for Fig. 7. The correct Fig. 7 is given below.

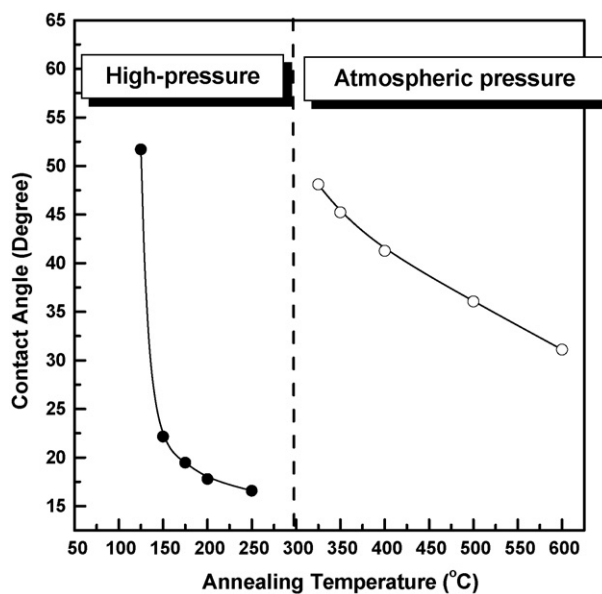


Fig. 7. Relations between contact angle and annealing temperature for TiO₂ thin films prepared under atmospheric pressure and via HPC process before UV light illumination.

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